

03500.017597.



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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: M. J. Song
MASAKI MIZUTANI, et al.)	
	:	Group Art Unit: 1722
Application No.: 10/670,301)	
	:	
Filed: September 26, 2003)	
	:	
For: METHOD FOR GROWING)	
SILICON FILM, METHOD FOR	:	
MANUFACTURING SOLAR)	
CELL, SEMICONDUCTOR	:	
SUBSTRATE, AND SOLAR)	
CELL	:	October 19, 2005

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

Sir:

In response to the restriction requirement set forth in the Office Action dated October 6, 2005, Applicants provisionally elect to prosecute the Group II claims, namely Claims 7 to 13. The restriction requirement is, however, traversed.

Traversal is on the ground that there would not be undue burden in examining the two groups of claims in a single application. In particular, MPEP § 808 makes clear that in order to require restriction between independent or distinct inventions, reasons for insisting upon a restriction requirement, such as undue burden, must also be shown. In the present instance, it is not believed that there would be an undue burden in

examining the claims of Groups I and II in a single application, since the two groups of claims are not so different as would require a burden on the Examiner that is significantly beyond that of the normal burdens of examination.

Accordingly, reconsideration and withdrawal of the restriction requirement are respectfully requested.

Applicants' undersigned attorney may be reached in our Costa Mesa, California office at (714) 540-8700. All correspondence should continue to be directed to our below-listed address.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Damond E. Vadnais", is written over a horizontal line.

Damond E. Vadnais
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